

The listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Previously Presented) A device for inspecting element substrates comprising a source of electromagnetic waves and an opposing detector substrate, the source of electromagnetic waves ionizing a gas present between the opposing detector substrate and an element substrate that is to be inspected,

wherein the opposing detector substrate has a TFT and an electrode connected to the TFT.

2. (Original) A device according to claim 1, wherein the source of electromagnetic waves generates electromagnetic waves or X-rays of a wavelength of from 0.01 to 100 nm.

3. (Previously Presented) A device according to claim 1, further comprising an ammeter for measuring an electric current between the opposing detector substrate and the element substrate through the ionized gas.

4. (Original) A device according to claim 1, wherein the opposing detector substrate has an opposing detector electrode.

5. (Original) A device according to claim 4, wherein the opposing detector electrode is made of a conductor that permits the transmission of electromagnetic waves or X-rays of a wavelength of 0.01 to 100 nm.

6. (Original) A device according to claim 5, wherein the opposing detector electrode is made of beryllium or aluminum.

7. (Original) A device according to claim 1, wherein the opposing detector substrate has plural TFTs and plural electrodes connected to the TFTs.

8.-9. (Canceled)

10. (Previously Presented) A method of inspecting element substrates by measuring an electric current between the element substrate and an opposing detector substrate through the ionized gas by using a device according to claim 1, thereby to inspect the current-flowing state of the pixel electrodes of the element substrate.

11. (Previously Presented) A method of inspecting element substrates by emitting electromagnetic waves from a source of electromagnetic waves in order to ionize a gas between the opposing detector substrate and the element substrate to be inspected,

wherein the opposing detector substrate has a TFT and an electrode connected to the TFT.

12. (Original) A method according to claim 11, wherein the source of electromagnetic waves generates electromagnetic waves or X-rays of a wavelength of 0.01 to 100 nm.

13. (Previously Presented) A method according to claim 11, wherein a current is measured between the opposing detector substrate and the element substrate through the ionized gas.

14.-15. (Canceled)

16. (Currently Amended) A device for inspecting element substrates comprising a source of electromagnetic waves and an opposing detector substrate, the source of electromagnetic waves ionizing a gas present between the opposing detector substrate and an element substrate that is to be inspected,

~~wherein a current control TFT is provided over the element substrate~~

wherein the opposing detector substrate has an opposing detector electrode, and

wherein the opposing detector electrode is made of a conductor that permits the transmission of electromagnetic waves or X-rays of a wavelength of 0.01 to 100 nm.

17. (Previously Presented) A device according to claim 16, wherein the source of electromagnetic waves generates electromagnetic waves or X-rays of a wavelength of from 0.01 to 100 nm.

18. (Previously Presented) A device according to claim 16, further comprising an ammeter for measuring an electric current between the opposing detector substrate and the element substrate through the ionized gas.

19.-20. (Canceled)

21. (Currently Amended) A device according to claim ~~[[20]]~~ 16, wherein the opposing detector electrode is made of beryllium or aluminum.

22. (Previously Presented) A device according to claim 16, wherein the opposing detector substrate has plural TFTs and plural electrodes connected to the TFTs.

23. (Currently Amended) A device for inspecting element substrates comprising a source of electromagnetic waves and an opposing detector substrate, the source of electromagnetic waves ionizing a gas present between the opposing detector substrate and an element substrate that is to be inspected,

~~wherein a current control TFT and a switching TFT are provided over the element substrate~~

wherein the opposing detector substrate has an opposing detector electrode, and

wherein the opposing detector electrode is made of beryllium or aluminum.

24. (Previously Presented) A device according to claim 23, wherein the source of electromagnetic waves generates electromagnetic waves or X-rays of a wavelength of from 0.01 to 100 nm.

25. (Previously Presented) A device according to claim 23, further comprising an ammeter for measuring an electric current between the opposing detector substrate and the element substrate through the ionized gas.

26. (Canceled)

27. (Previously Presented) A device according to claim ~~[[26]]~~ 23, wherein the opposing detector electrode is made of a conductor that permits the transmission of electromagnetic waves or X-rays of a wavelength of 0.01 to 100 nm.

28. (Canceled)

29. (Previously Presented) A device according to claim 23, wherein the opposing detector substrate has plural TFTs and plural electrodes connected to the TFTs.